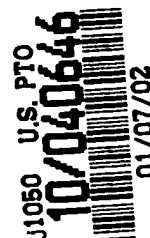


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9-4-02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re Application of:)	PATENT APPLICATION
)	
Inventors: Hirohiko Nishiki, James M.)	
Atkinson and Yukihiro Nakata)	
)	
Serial No.: Not Yet Assigned)	Attorney Docket No.
)	SLA 0452
Filed: Herewith)	
)	
Title: SYSTEM AND METHOD FOR)	
ETCHING RESIN WITH AN)	
OZONE WET ETCHING)	
PROCESS)	

Hon. Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Sir:

Listed on attached Form PTO-1449 is information submitted pursuant to
37 C.F.R. §1.56. A copy of each listed publication is submitted herewith.

Applicant respectfully requests that the listed information be considered by
the Examiner and made of record in the above-identified application.

(Date) 1/7/02

Respectfully submitted,

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